

# Suppression of crosstalk in SiPMs for the next generation gamma-ray observatory, CTA

Hiro Tajima, Akira Okumura, Yuki Nakamura, Anatolii Zenin,  
Nagoya University (for the CTA-Japan Consortium)

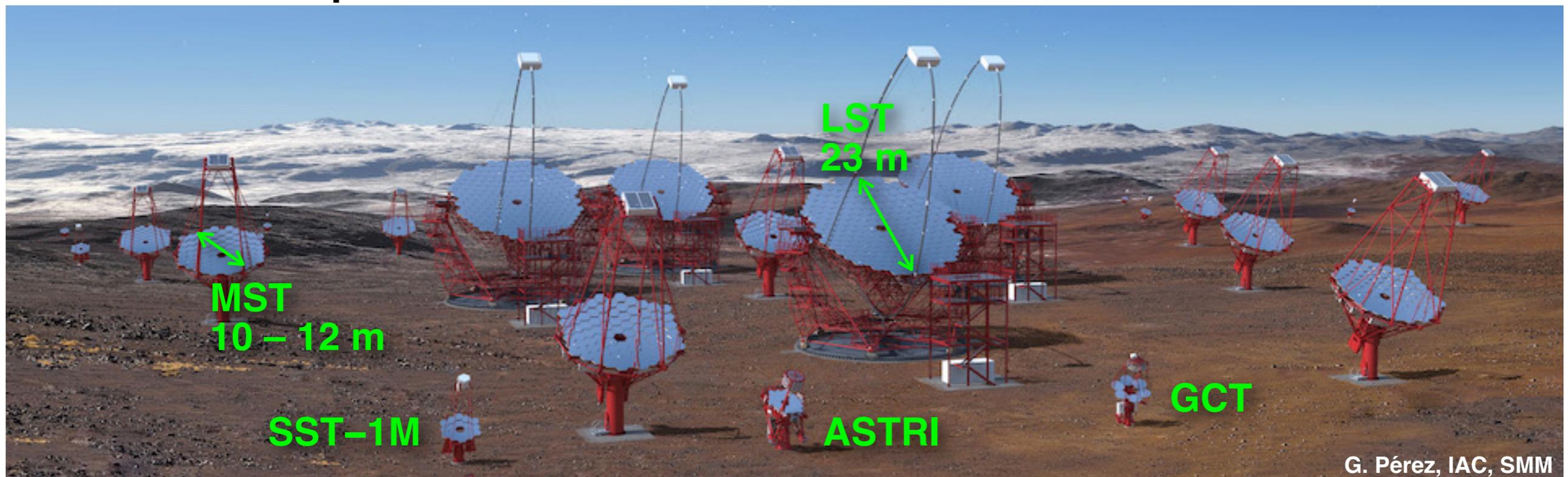
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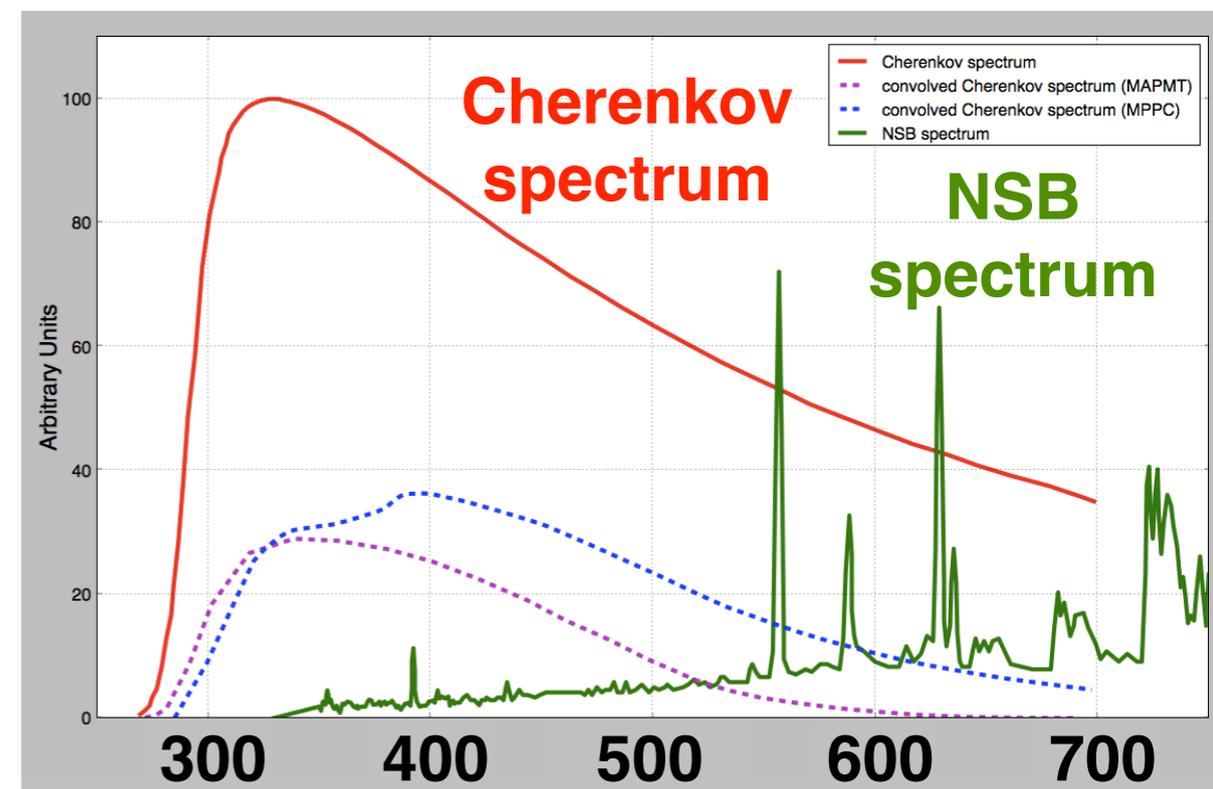


- ❖ Observations of gamma rays in 20 GeV – 300 TeV band
  - ❖ Cherenkov light from electromagnetic shower produced by interaction of gamma rays with atmosphere
- ❖ Large collection area by placing many telescopes
  - ❖ **×10 better sensitivity than current instruments**
- ❖ Wide energy band coverage by three different sizes of telescopes
  - ❖ Large-sized telescope (LST):  $\Phi = 23$  m, 20 GeV – 1 TeV, 4 telescopes
  - ❖ Medium-sized telescope (MST):  $\Phi = 10 - 12$  m, 0.1 – 10 TeV, ~20 telescopes
  - ❖ **Small-sized telescope (SST):  $\Phi = 4$  m, 1 – >300 TeV, 50 – 70 telescopes**  
all SSTs are placed at south site



G. Pérez, IAC, SMM

- ❖ **Properties of Cherenkov photons from gamma-ray air shower**
  - ❖ ~500 photons/m<sup>2</sup> for 10 TeV gamma-ray shower
  - ❖ Several photons per pixel
  - ❖ Cherenkov photons **peaks around ~350 nm**
    - ◆ **Blue to near UV sensitivity is important**
  - ❖ Cherenkov photons arrives within a few to few tens of ns
    - ◆ **ns-timing is important**
- ❖ **Night sky background (NSB) is the dominant background**
  - ❖ **Rate is >25 MHz/pixel**
    - ◆ Dark count rate is not important
    - ◆ [NSB] x [Optical crosstalk (OCT)] can cause false triggers due to accidental coincidences
      - **Low OCT rate is important**
  - ❖ NSB peaks **above 550 nm**
    - ◆ **Low red sensitivity is preferred**



❖ **Silicon Photomultiplier** is chosen as a photon sensor for SST

- ❖ Cost per channel
- ❖ Photon detection efficiency
- ❖ Tolerance against **high rate environment (> 25 MHz per pixel)**
- ❖ Reliability

❖ Major drawback of SiPM

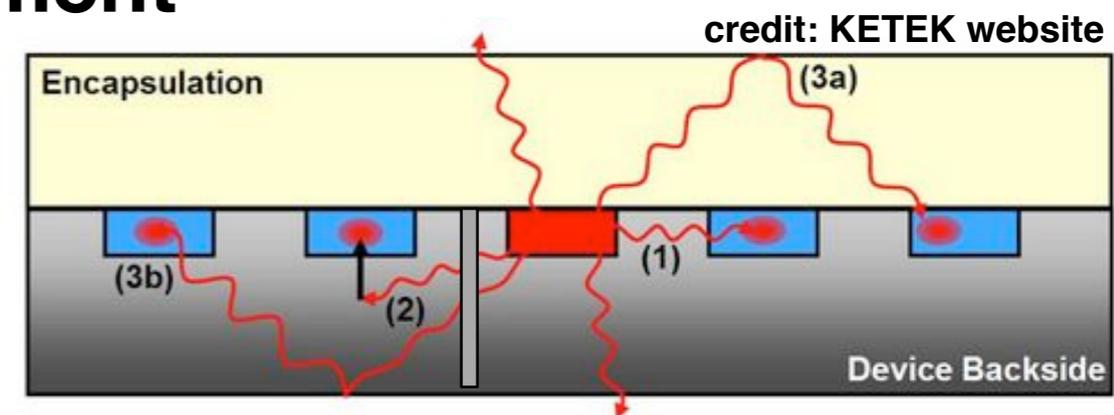
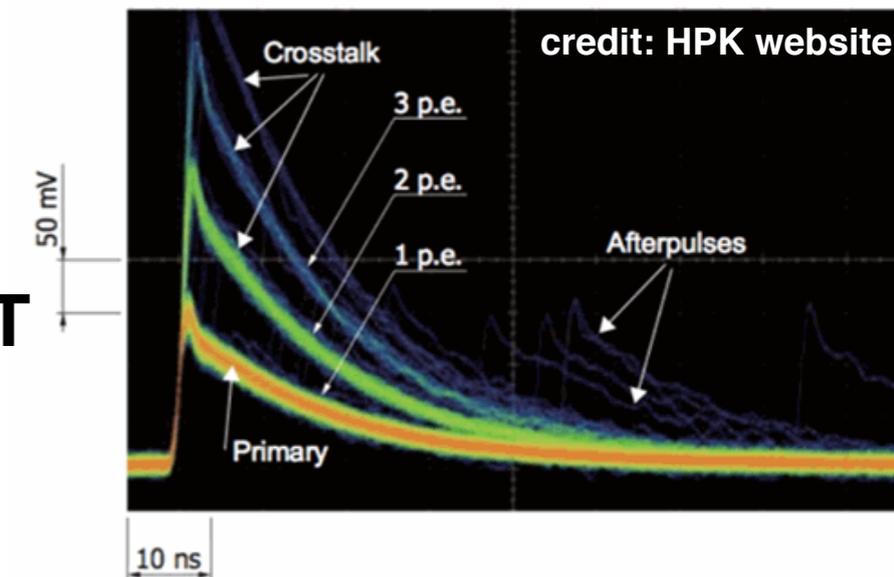
❖ **Optical crosstalk (OCT)**

- ❖ High rate night sky background (NSB) + OCT can cause false triggers due to accidental coincidences

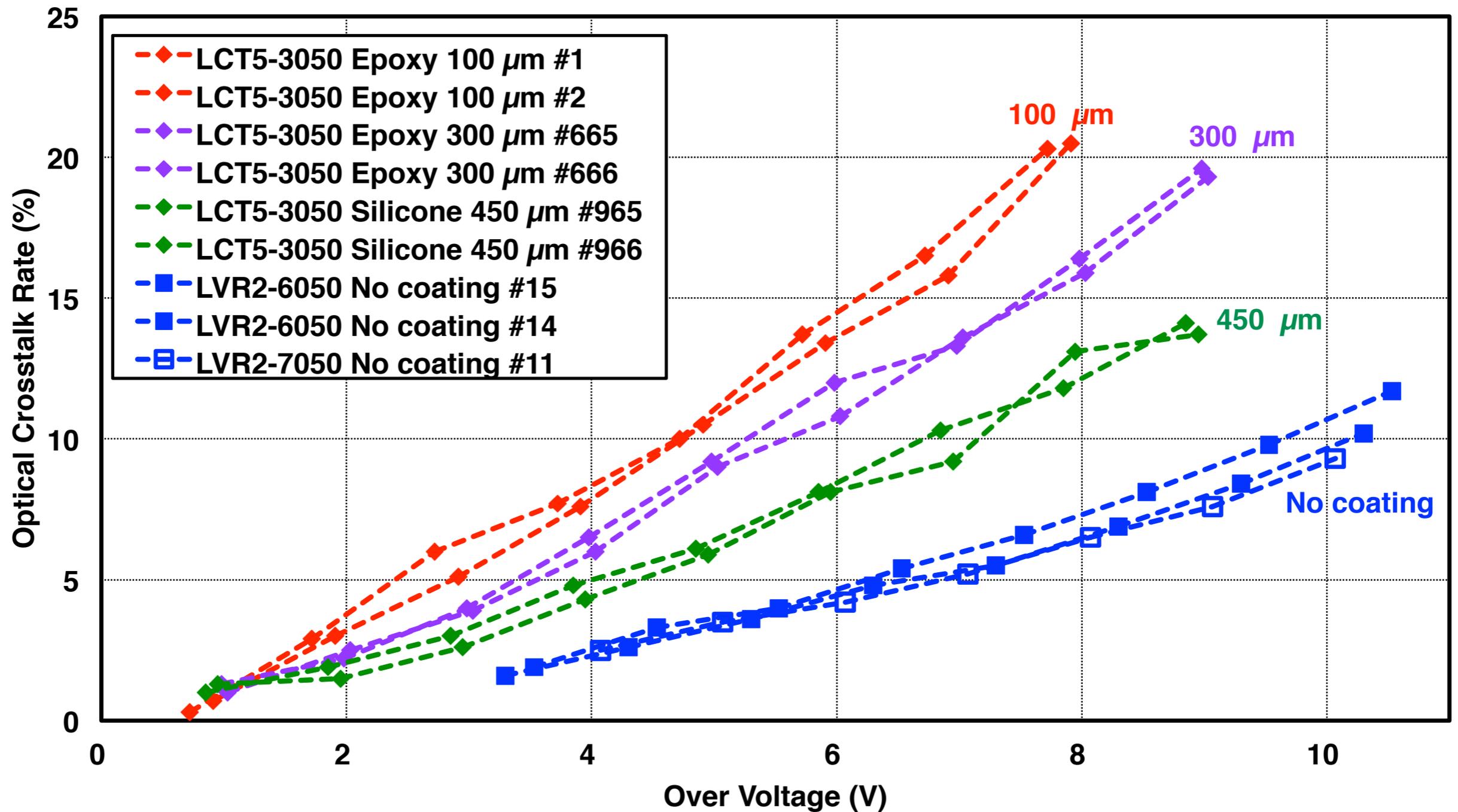
- ❖ Gain dependence on the temperature
- ❖ High sensitivities for red light (NSB wavelength)

❖ Main objective of CTA SiPM development

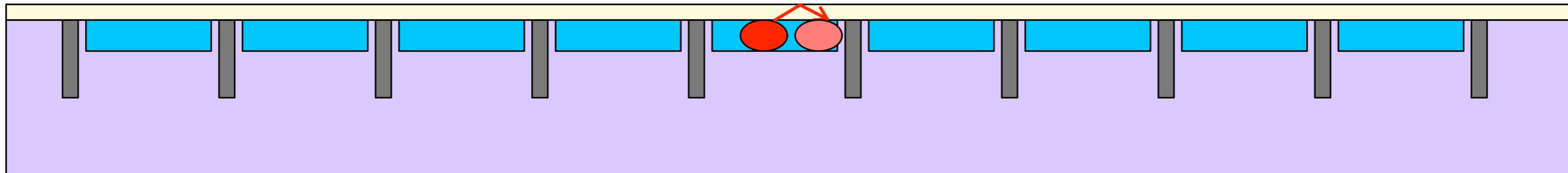
- ❖ **Suppress OCT while retaining photon detection efficiency (PDE)**



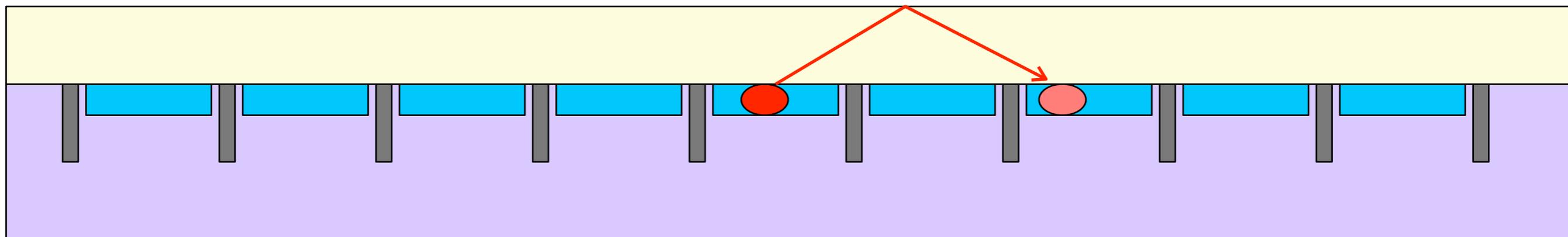
## ❖ Thicker coating or no coating give lower crosstalk



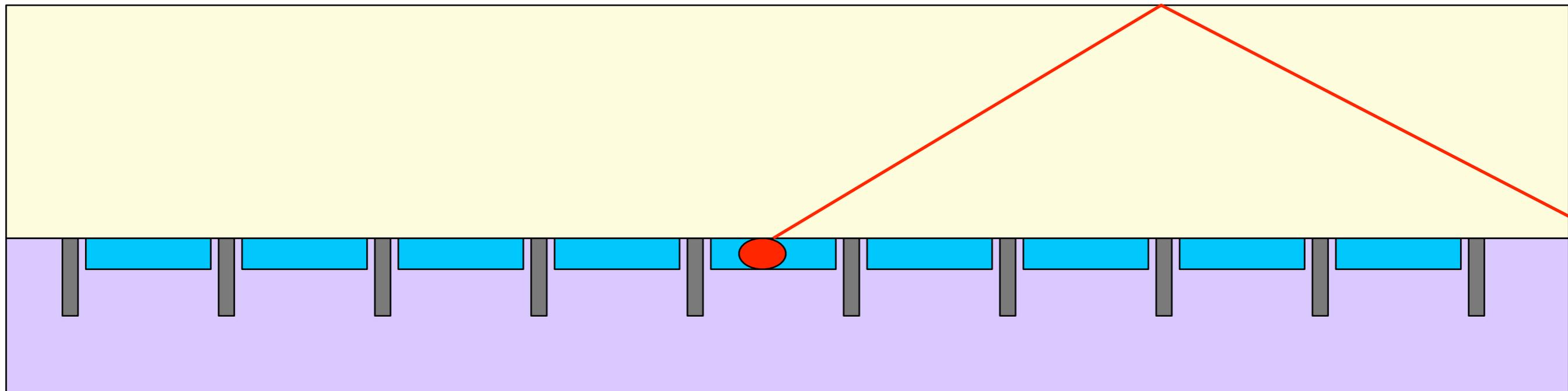
- ❖ **No coating (or very thin coating)**
  - ❖ Reflected photons come back to the original cell
- ❖ **Intermediate thickness**
  - ❖ Photons reflected by the air interface may produce avalanches in other cells
- ❖ **Very thick coating**
  - ❖ Photons reflected by the air interface may get out of the device
  - ❖ Smaller device may have lower crosstalk rate
- ❖ **How about the crosstalk from the backside?**



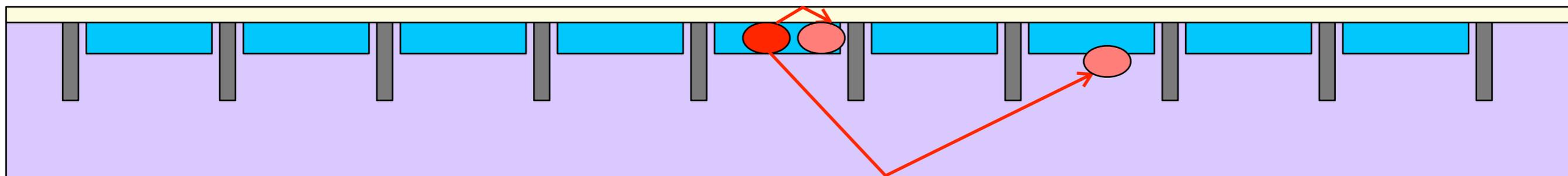
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- ❖ We have systematically investigated the OCT rate with varying device size, cell size, and with and without coating
- ❖ OCT rate is expected to be proportional to the number of electron-holes pairs (=charge) produced in an avalanche
  - ◆ proportional to a product of [cell capacitance] and [over voltage]
- ❖ Find out propagation properties of crosstalk photons

Product ID	Device size	Cell size	Coating	Fill factor
S14520-3050VS	3 mm	50 $\mu\text{m}$	300 $\mu\text{m}$	74%
S14520-3050VN	3 mm	50 $\mu\text{m}$	None	74%
S14520-3075VS	3 mm	75 $\mu\text{m}$	300 $\mu\text{m}$	82%
S14520-3075VN	3 mm	75 $\mu\text{m}$	None	82%
S14520-6050VS	6 mm	50 $\mu\text{m}$	300 $\mu\text{m}$	74%
S14520-6050VN	6 mm	50 $\mu\text{m}$	None	74%
S14520-6075VS	6 mm	75 $\mu\text{m}$	300 $\mu\text{m}$	82%
S14520-6075VN	6 mm	75 $\mu\text{m}$	None	82%

## ❖ Take waveform data by digital oscilloscope

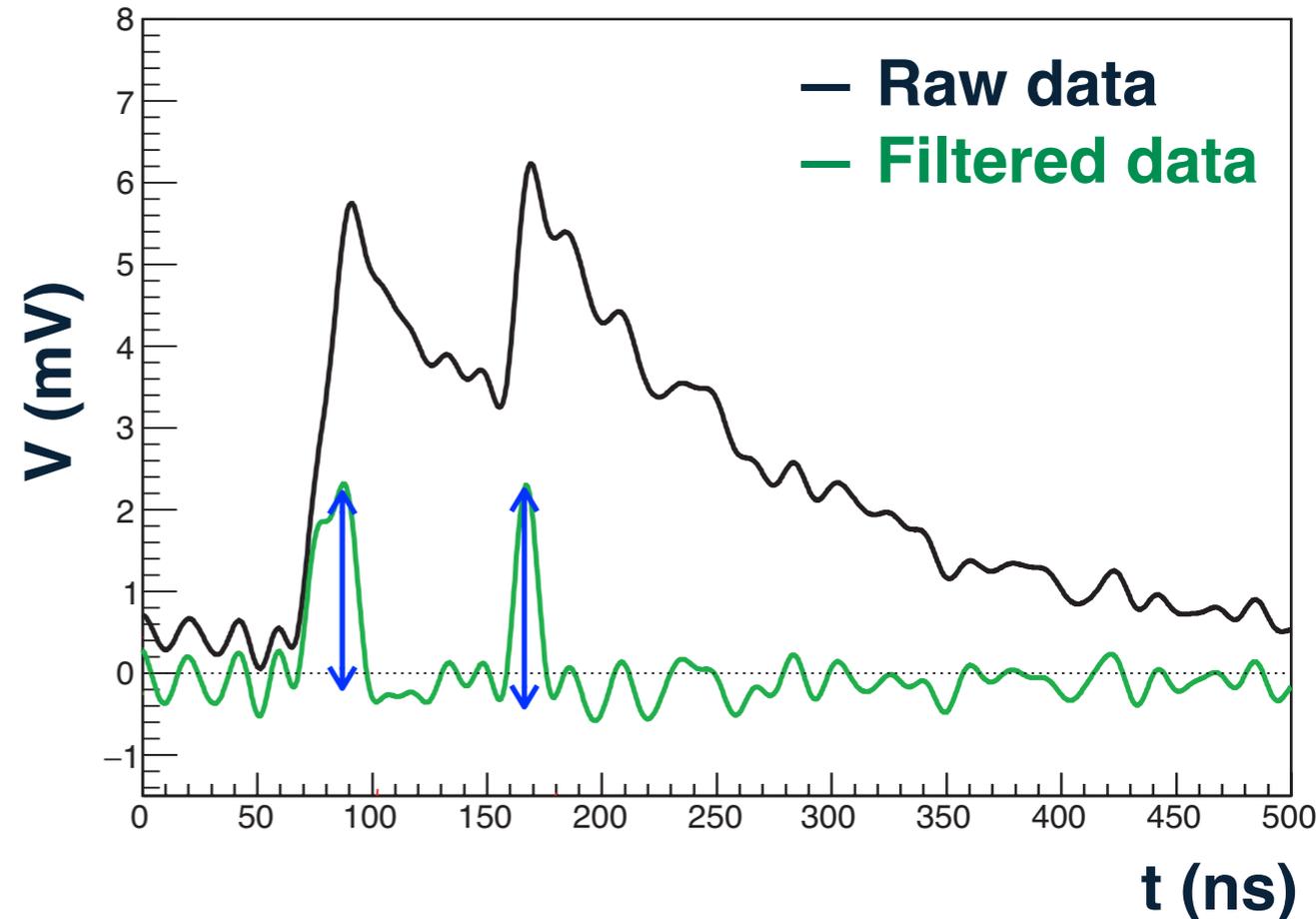
### ❖ Offline data analysis

◆ **Digital filter** to minimize the effect of pile ups

◆ **Pulse analysis**

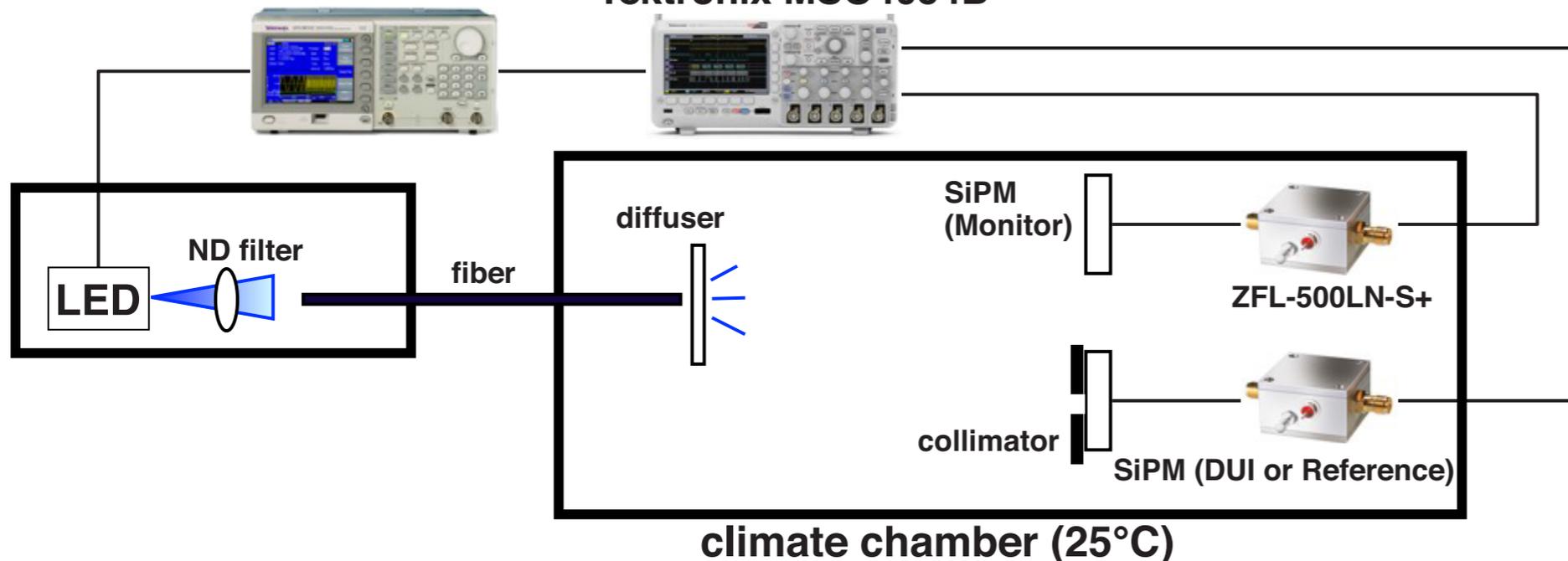
## ❖ Light output is monitored

## ❖ Wavelength is fixed at 405 nm for this measurement



Pulse Generator  
Tektronix AFG 3251

Oscilloscope  
Tektronix MSO4054B



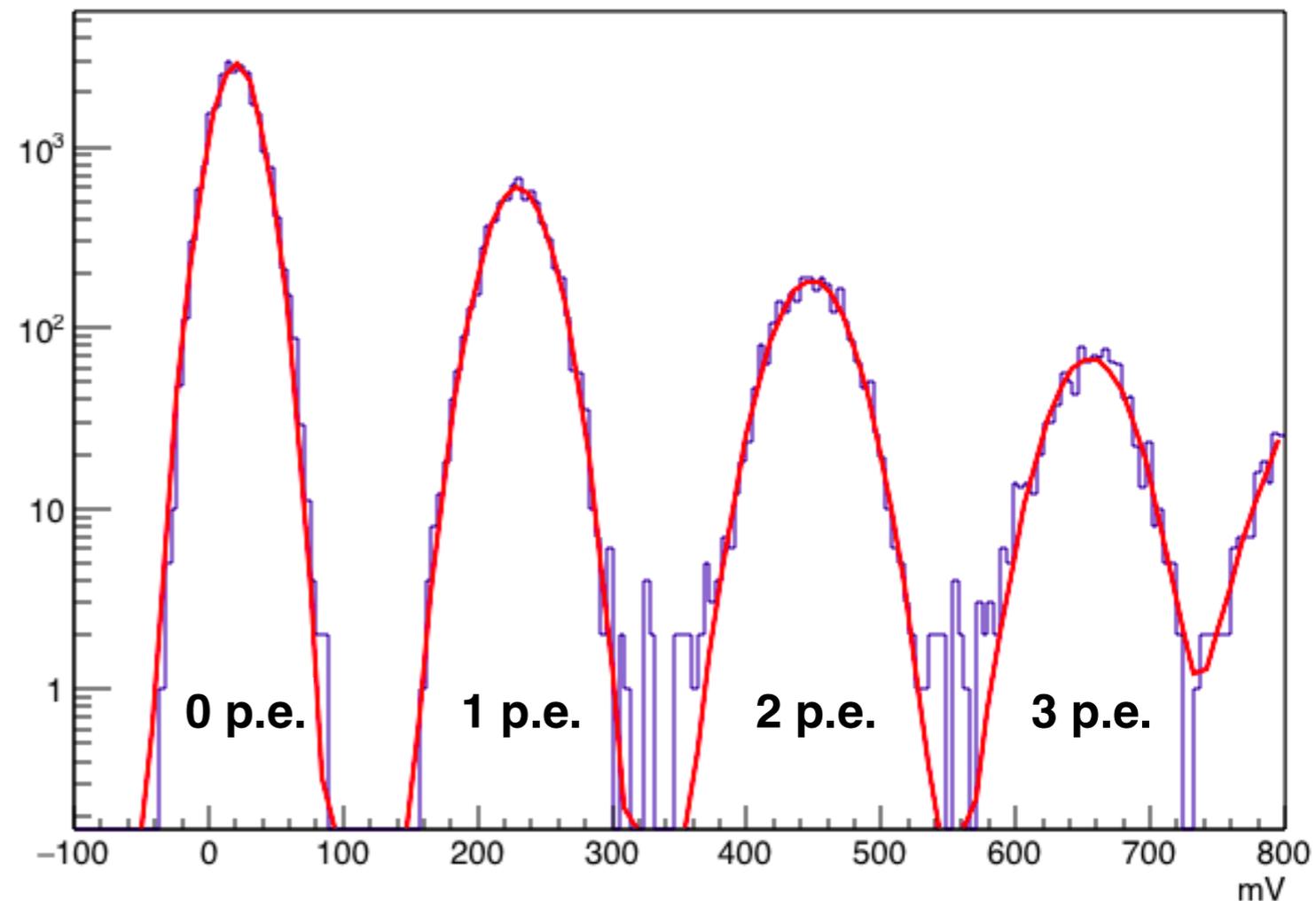
- ❖ We measure number of photons for short LED (or laser) pulses
  - ❖ Current measurement does not provide accurate PDE due to optical crosstalk, delayed cross talk and after pulse
- ❖ Number of photo electrons (p.e.) does not follow Poisson distribution due to optical crosstalk
  - ❖ **Probability of 0 p.e.** is used to obtain the average to avoid effects of optical crosstalk
  - ❖ **Effect of dark count** still need to be taken into account

$$P(n) = e^{-\mu} \mu^n / n!$$

$$P(0) = e^{-\mu}$$

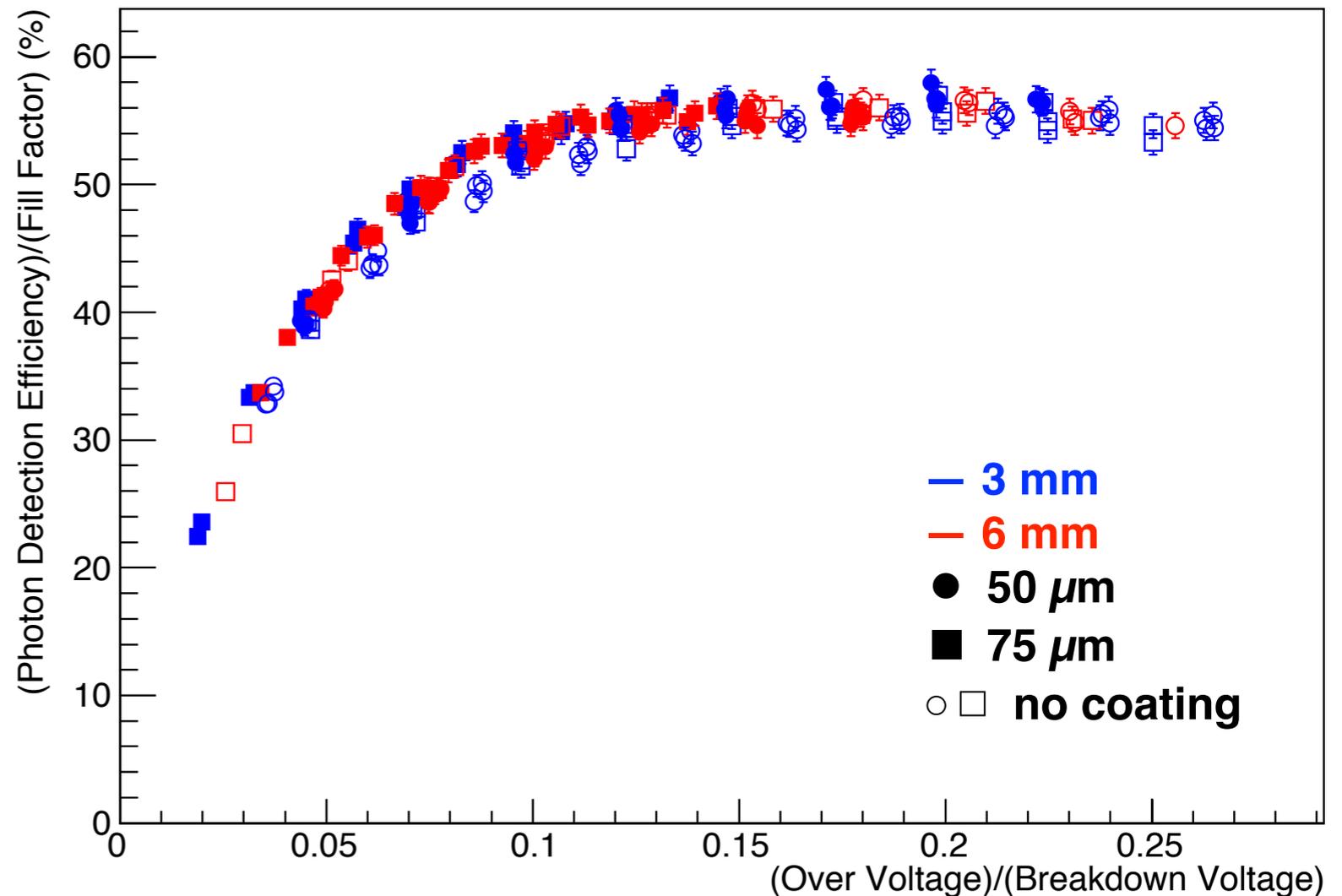
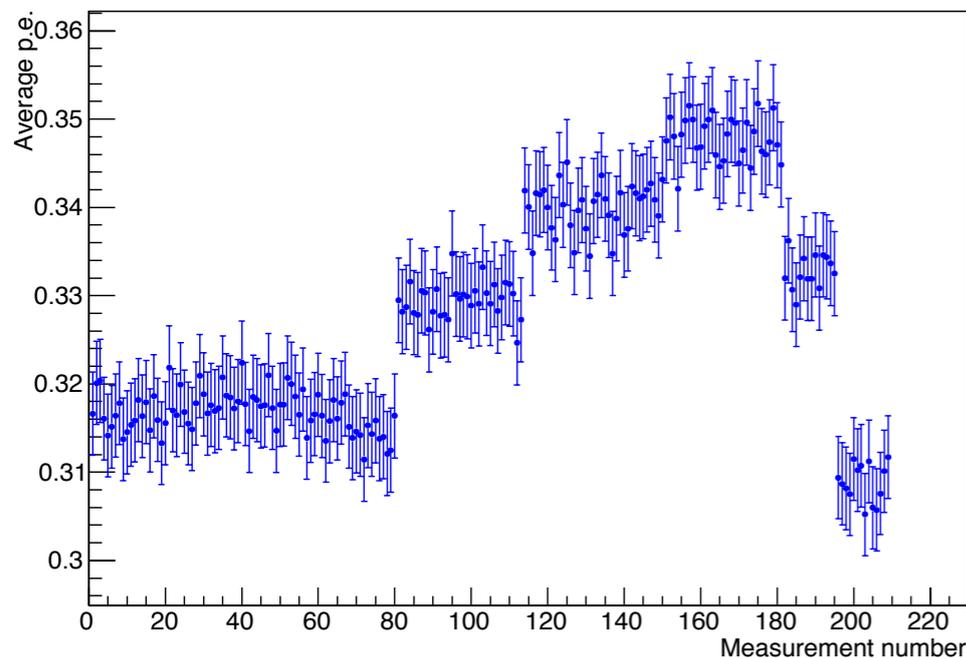
$$\mu = -\ln(P(0))$$

$$P_{\text{true}}(0) = P_{\text{ON}}(0) / P_{\text{OFF}}(0)$$



- ❖ PDEs were measured for 2 devices for each type
- ❖ PDEs were measured twice for one device
- ❖ Measured PDEs were very consistent, which indicates varying light intensity is properly compensated by the monitor SiPM

Average p.e. for Monitor SiPM



- ❖ Assume 1 p.e. peak of dark signal is dominated by dark count
- ❖ 2 p.e. peak consists of optical crosstalk from 1 p.e. and chance coincidence of dark counts within  $\Delta t_{PS}$  ( $\sim 3$  ns in our setup)

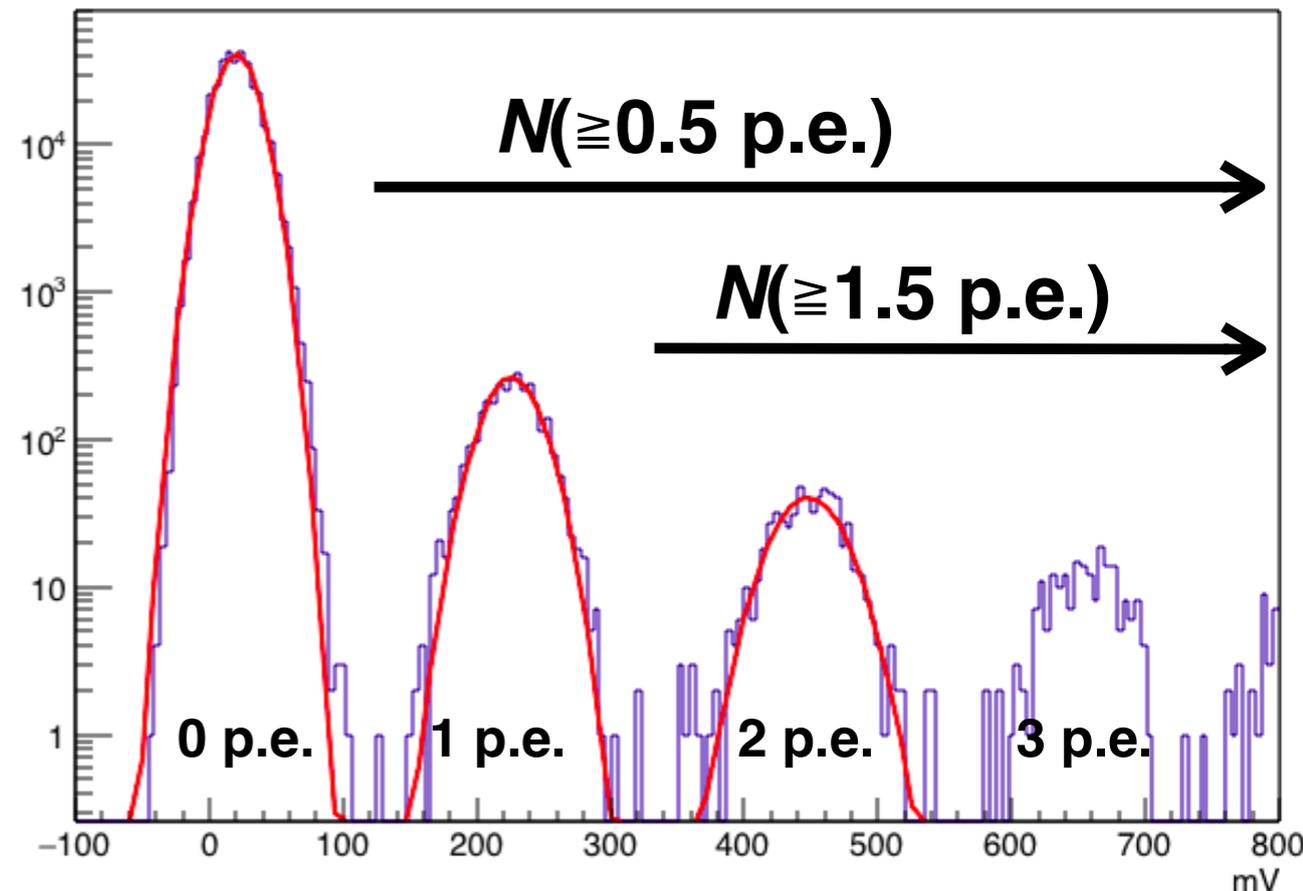
Probability to have no optical crosstalk

$$\frac{N(\geq 1.5 \text{ p.e.})}{N(\geq 0.5 \text{ p.e.})} = 1 - \boxed{(1 - R_{OCT})e^{-f_{DC}\Delta t_{PS}}} \leftarrow \text{Poisson probability to have no overlapping dark count within } \Delta t_{PS}$$

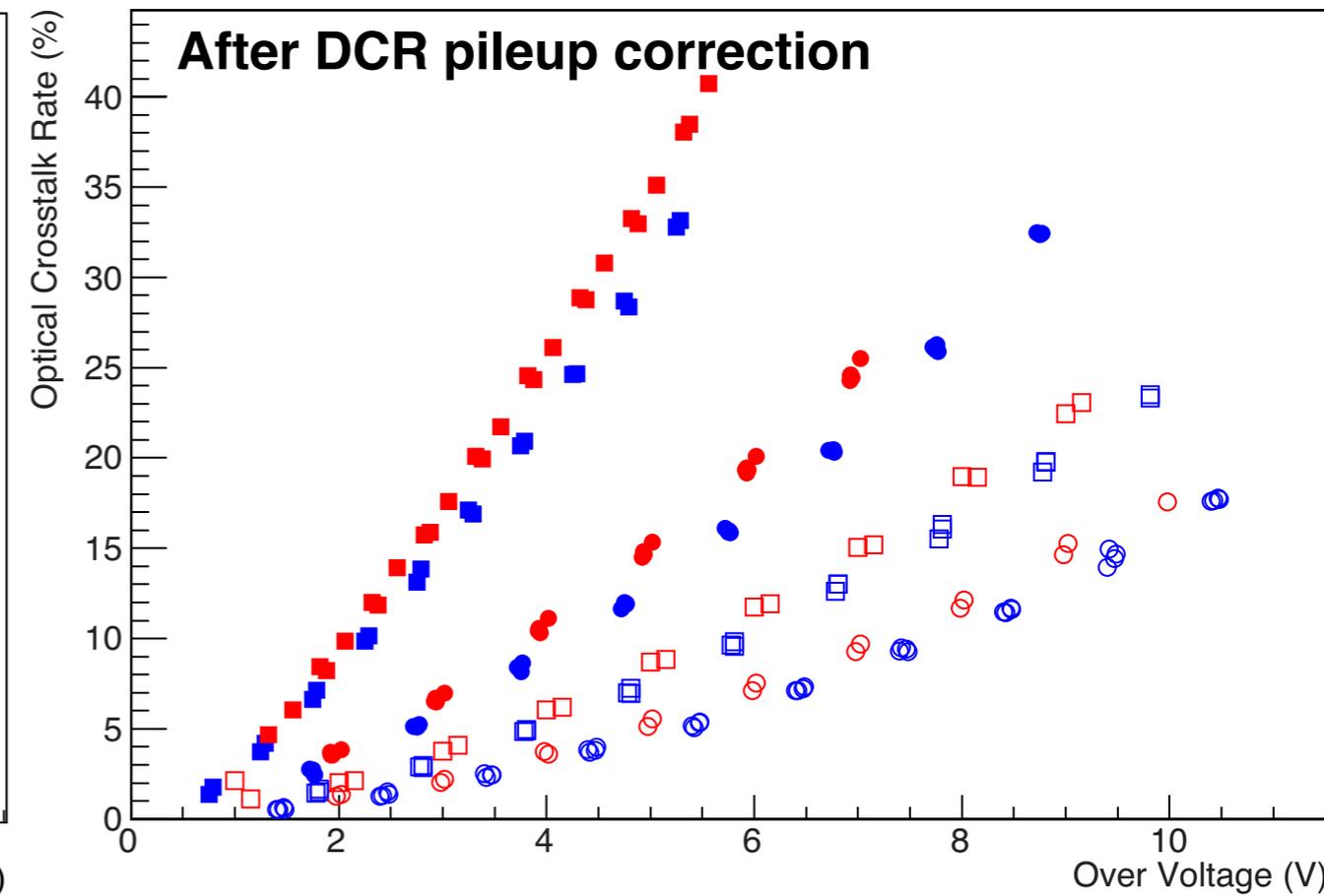
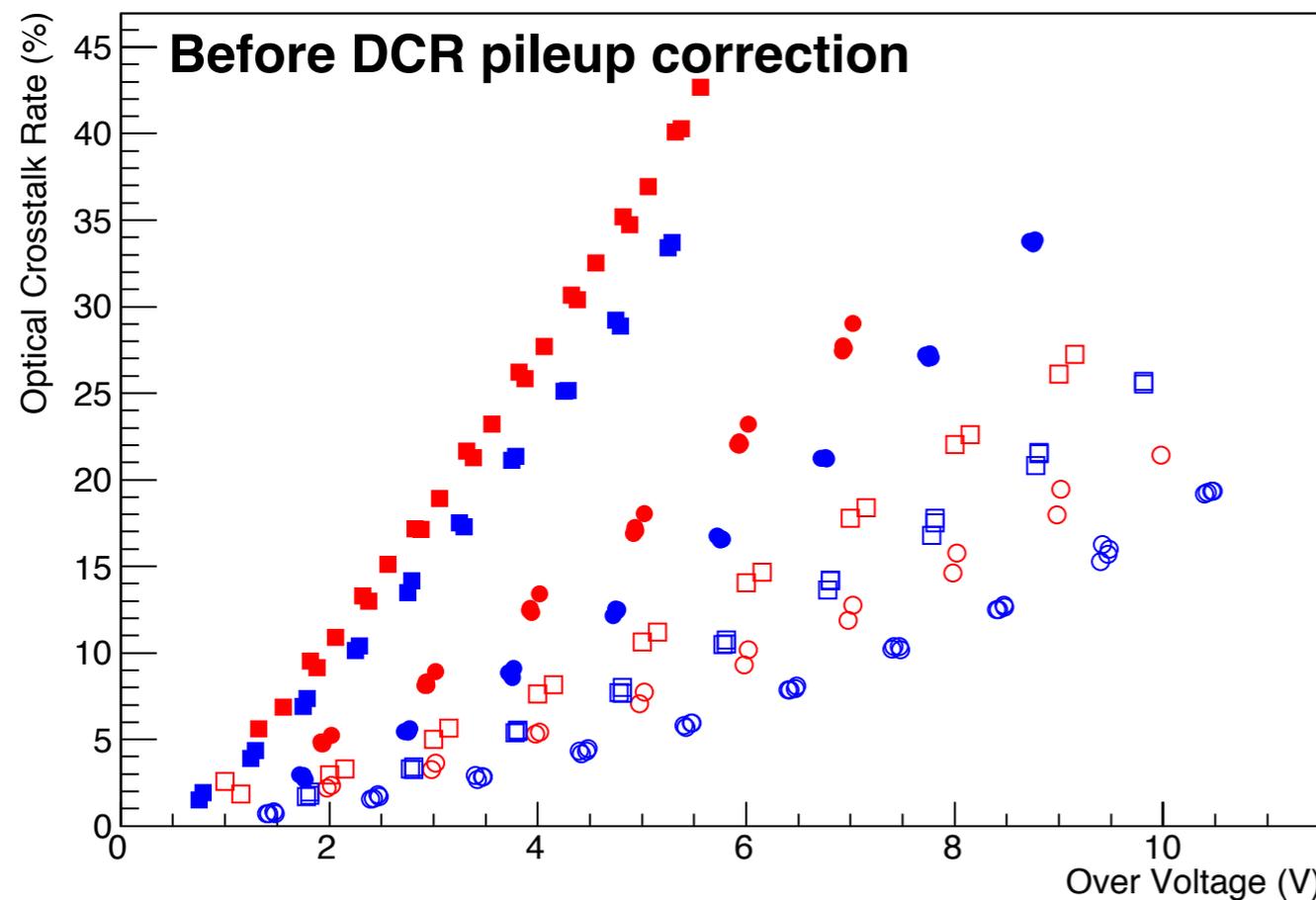
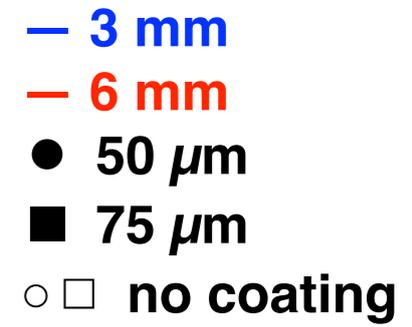
$$R_{OCT} = 1 - \left( 1 - \frac{N(\geq 1.5 \text{ p.e.})}{N(\geq 0.5 \text{ p.e.})} \right) / e^{-f_{DC}\Delta t_{PS}}$$

$f_{DC}$ : Dark count rate

$\Delta t_{PS}$ : Double-pulse separation time

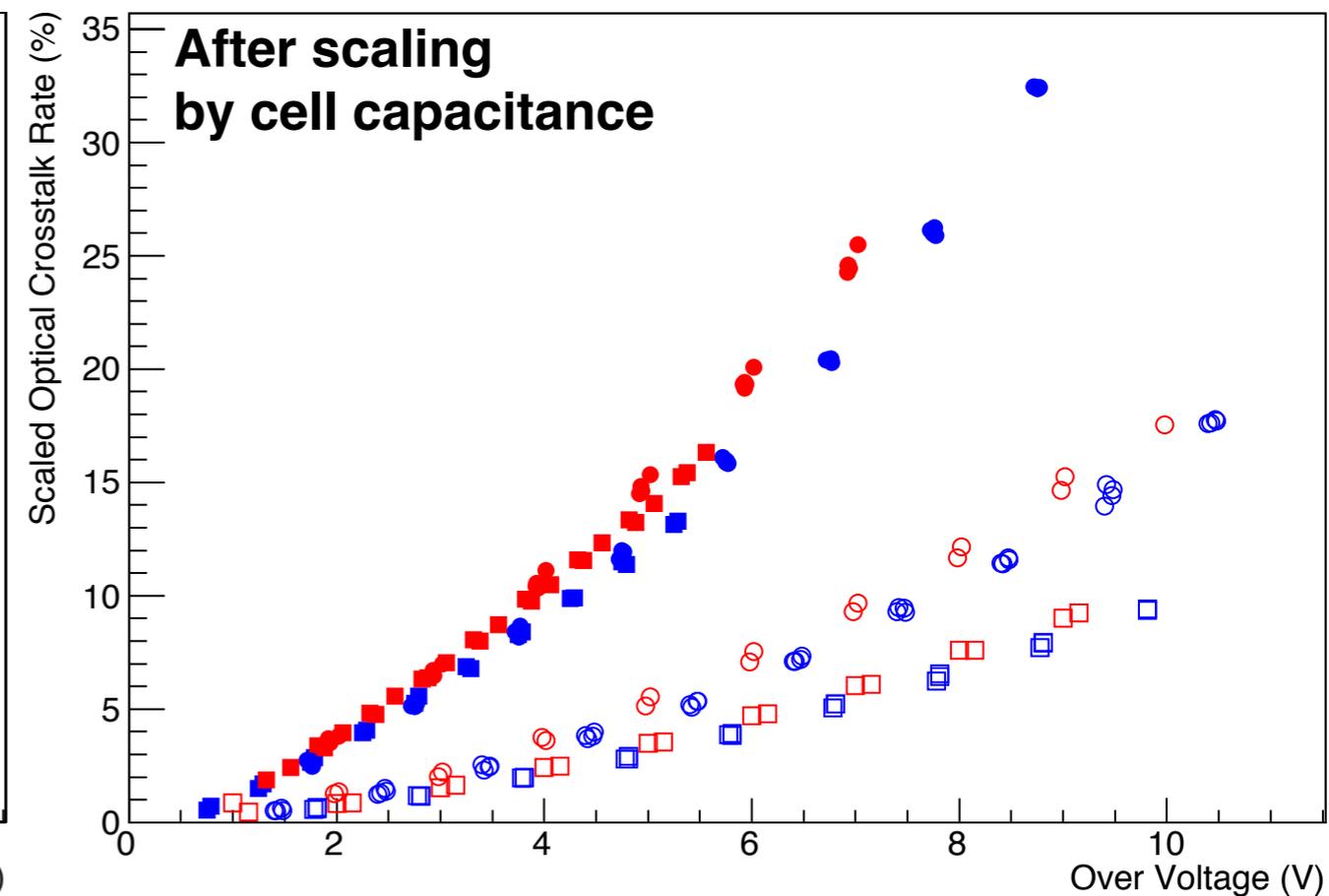
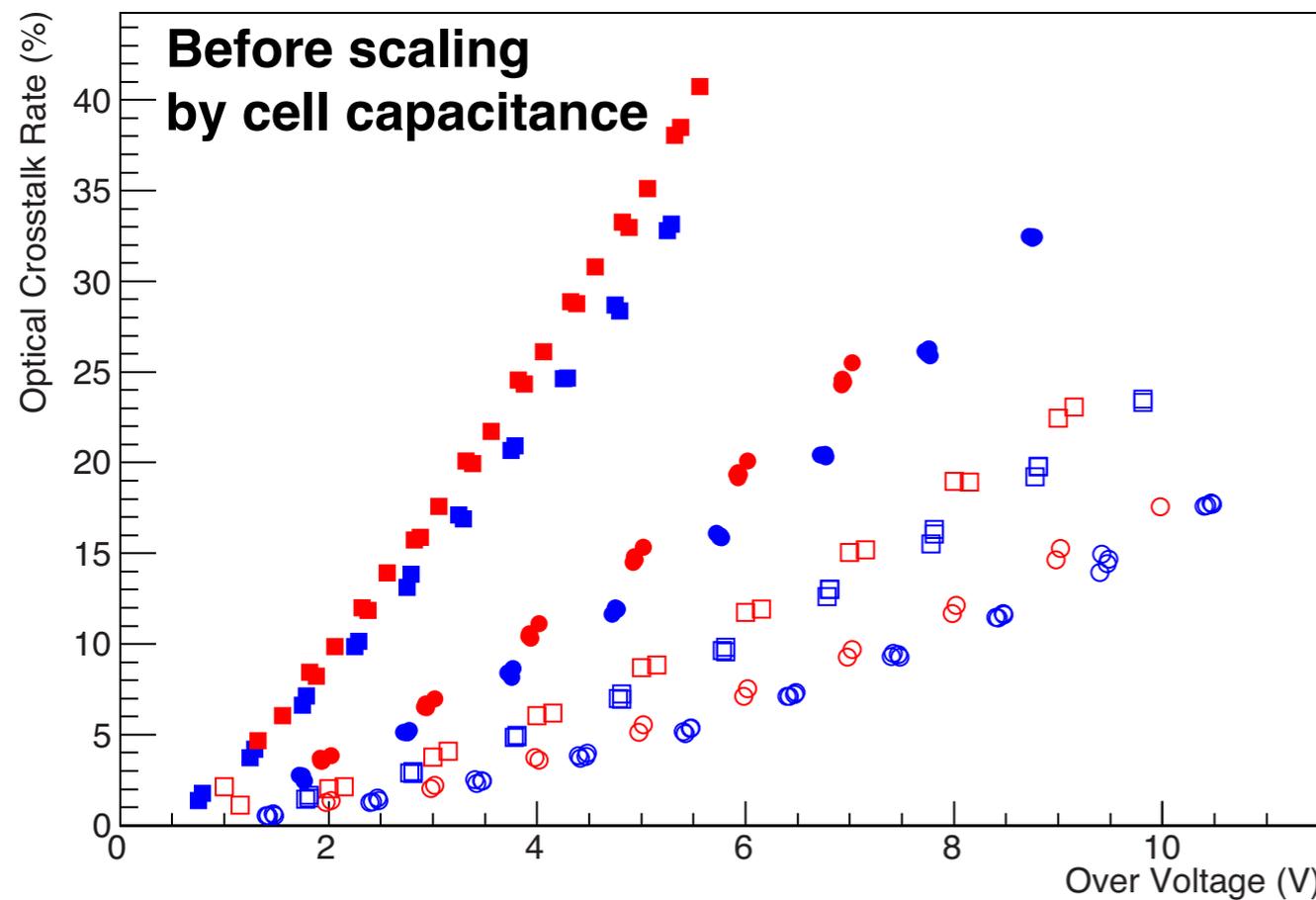


- ❖ Dark count pileup correction works well
- ❖ Factor out **cell capacitance** dependence of crosstalk rate by scaling it with **cell area and depth** (assuming cell depth  $\propto$  break down voltage)
  - ❖ 3 mm device gives slightly lower OCT than 6 mm device
  - ❖ OCT rate scales very well with cell capacitance with coating
    - ◆ Not so without coating
  - ❖ Differences among individual SiPMs are small



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- 3 mm
- 6 mm
- 50  $\mu\text{m}$
- 75  $\mu\text{m}$
- □ no coating



❖ Optical crosstalk rate should be proportional to the charge produced in the avalanche and avalanche trigger probability

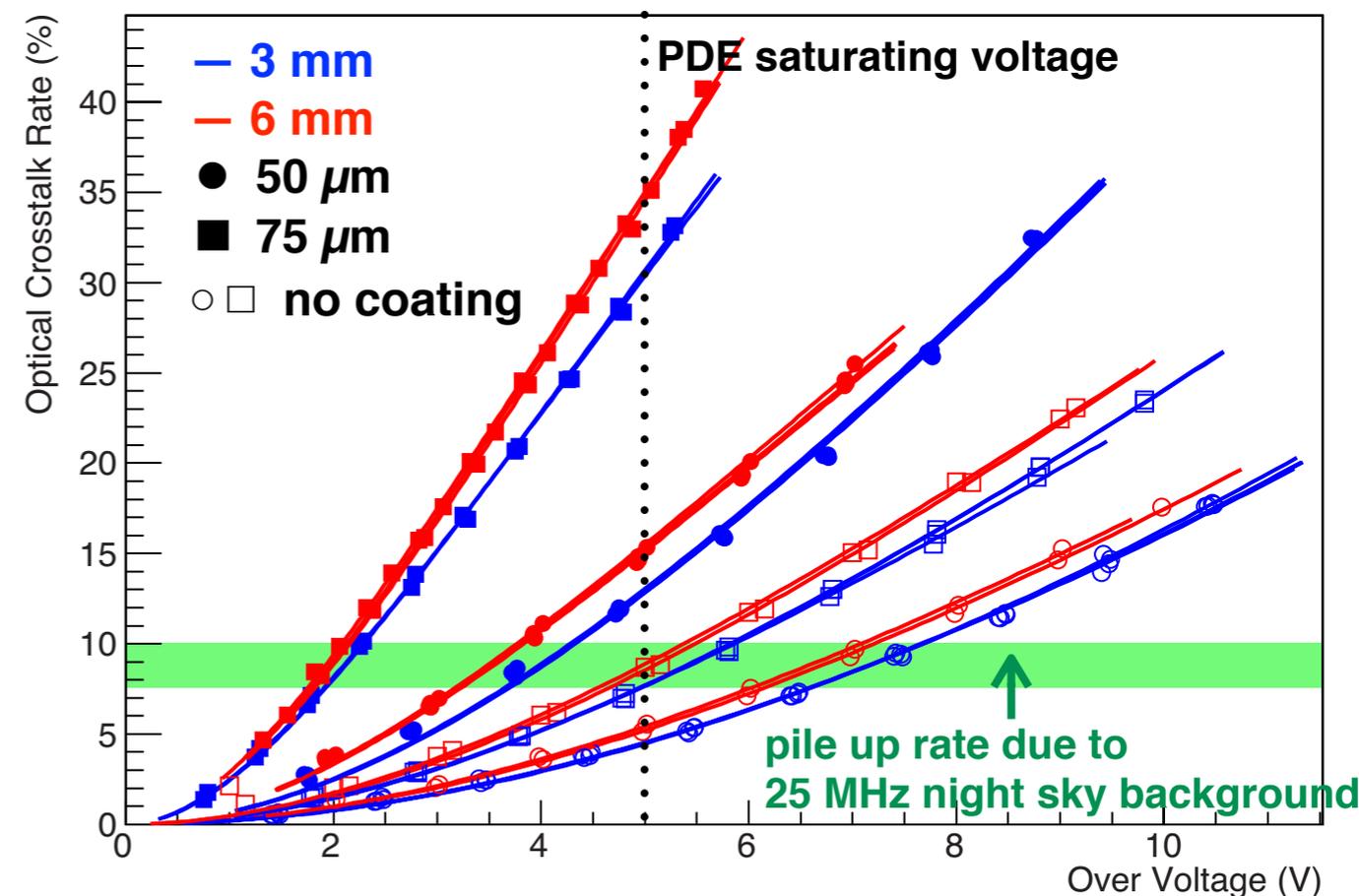
$$R_{OCT} = C_{OCT} \cdot \underbrace{(\text{Fill factor}) \cdot (\text{Cell size})^2 / V_{BR}}_{\propto \text{cell capacitor}} \cdot V_{OV} \cdot \underbrace{(1 - \exp[-C'_{Otte} V_{OV} / V_{BR}])}_{\text{Avalanche probability}}$$

❖  $C_{OCT}$  is smaller for 75  $\mu\text{m}$  cells (**smaller crosstalk efficiency**)

❖  $C_{Otte}$  is smaller without coating

◆ **Avalanche seed is produced in the region where it is harder to trigger avalanche**

Product ID	$C_{OCT}$	$C_{Otte}$
S14520-3050VS	0.1	5
S14520-6050VS	0.09	10
S14520-3075VS	0.06	18
S14520-6075VS	0.07	17
S14520-3050VN	0.09	2
S14520-6050VN	0.07	3
S14520-3075VN	0.03	5
S14520-6075VN	0.03	5



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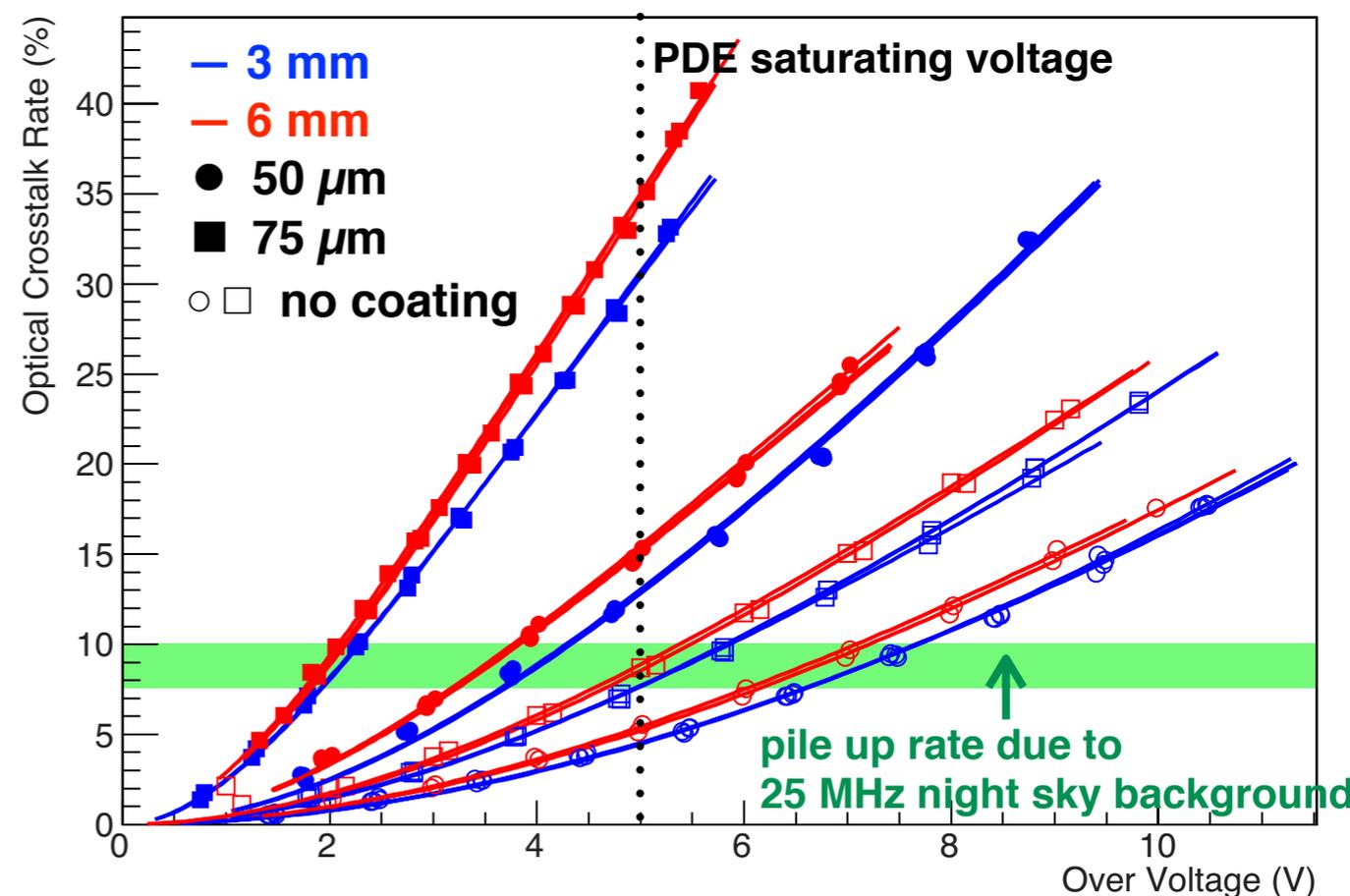
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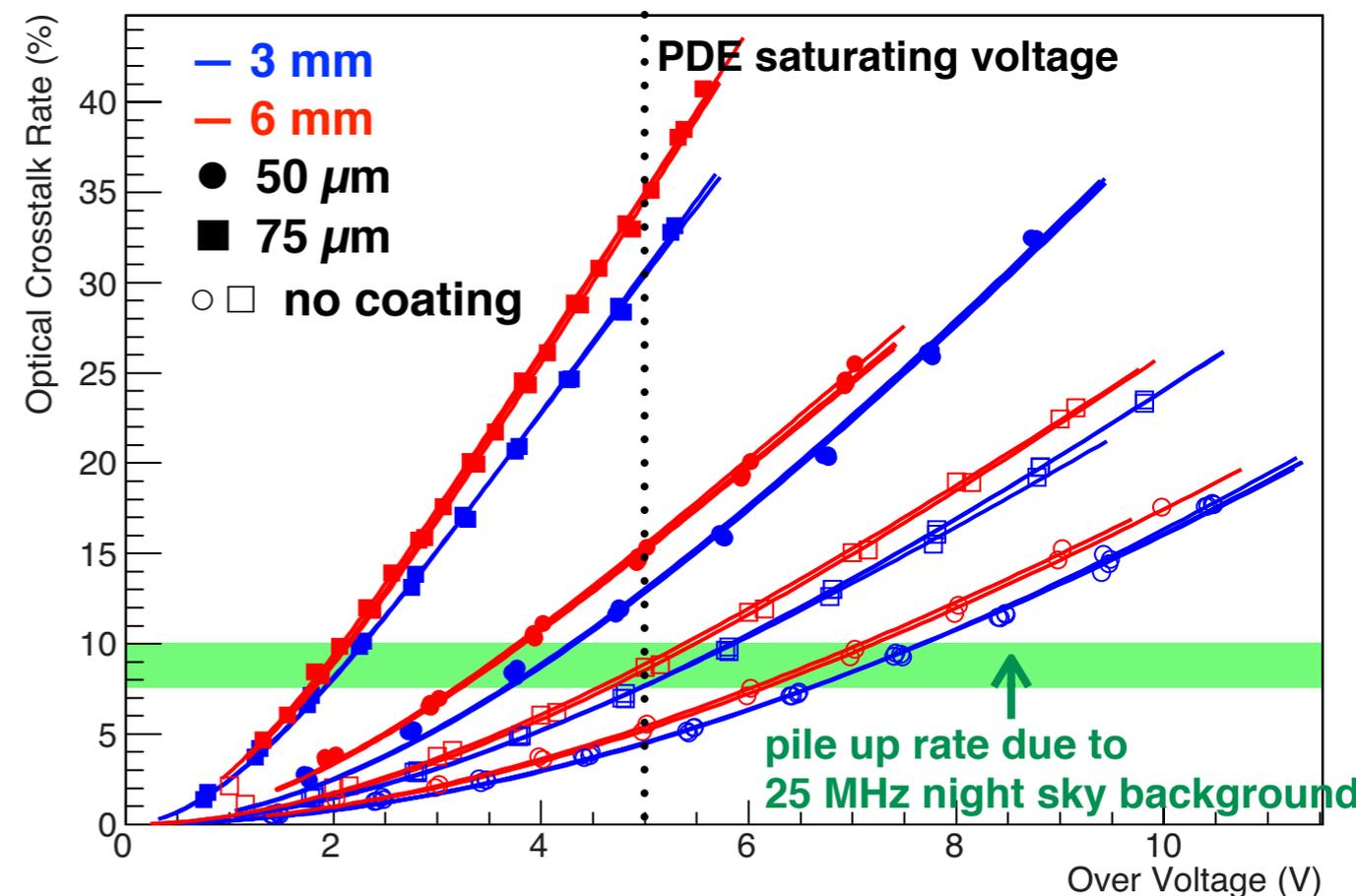
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- ❖ **Optical crosstalk rate is significantly affected by protection coating**
  - ❖ **Smaller device size and thicker coating** reduce OCT rate
  - ❖ Larger cell size increase OCT rate, but not proportional to the cell area
  - ❖ **No coating** significantly reduces OCT rate
    - ◆ OCT rate does not scale with the cell size
    - ◆ OCT seeds are produced in the region where avalanche trigger probability is low
  
- ❖ **Prospects**
  - ❖ **6 mm device with 75  $\mu\text{m}$  cell without coating may be the best choice for CTA**
    - ◆ Without protective coating, damages on the SiPM surface are of major concerns
      - We put a piece of protective film to avoid damages during the assembly handling
      - Damages during observations can be avoided by the UV transparent shield on the camera front  
(This shield will also act as a filter for red lights.)
  - ❖ Further reduction of OCT by suppressing crosstalk due to photons reflected at the backside of SiPM

